

PROCEEDINGS OF SPIE

# ***Optical System Alignment and Tolerancing***

**José M. Sasian**  
**Mitchell C. Ruda**  
*Editors*

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## Introduction

This is the first year that the Optical Systems Alignment and Tolerancing conference is offered and it has been a success. The previous conference series in Optical Alignment are missed and we are refreshing the topic by adding the critical subject of tolerancing as it goes hand in hand with alignment.

Current technology is broad and expanding. As optical systems continue to require higher performance, the challenges for optical alignment and tolerancing are growing as well.

The Optical Systems Alignment and Tolerancing conference intends to provide a forum where past and current knowledge about optical alignment and tolerancing is discussed. In this first year we had papers ranging from traditional alignment to new areas such as nano-alignment. The overall conference was perceived as very useful and the audience provided positive feedback. The reader can browse and read the papers in this volume to benefit from the authors' expertise. We thank the authors, the audience, the committee, and SPIE for making this conference a success. We are looking forward to next year's conference in Optical Systems Alignment and Tolerancing.

**José M. Sasian**  
**Mitchell C. Ruda**

